

In the United States Patent and Trademark Office

Serial No. 10/550,855	§	Filing date: 09/18/2006
	§	
Title: FORMATION OF THIN SEMI-CONDUCTOR LAYERS BY LOW-ENERGY PLASMA ENHANCED	§	Examiner: McCall Shepard, Sonya D
CHEMICAL VAPOR DEPOSITION	§	GA No.: 1734
AND SEMICONDUCTOR HETERO-STRUCTURE DEVICES	§	Confirmation No. 3611
	§	
Applicant: VON KAENEL, Hans	§	Atty docket No: PUS-E005-013

CERTIFICATE OF TRANSMISSION UNDER 37 CFR §1.8. I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office, as _____ pages, total,

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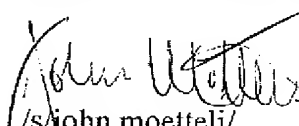
Dear Sir,

Applicant thanks the Office for the Restriction Requirement dated March 24, 2009, and in response thereto, Applicant elects, without traverse, Group I, which reads on claims 1-17, for further prosecution.

The Undersigned authorizes the Commissioner to charge any fee or credit any overpayment of any fee under 37 CFR §1.16 which may be required in this application, to the deposit account of MOETTELI & ASSOCIES SARL, No. 50-2621.

If the Examiner has further questions, she is invited to contact the undersigned by email at moetteli@patentinfo.net (preferred) or by phone at 202-204-2222.

Respectfully submitted,



/s/ John Moetteli/
John Moetteli
U.S. Reg. No. 35,289

Date: April 23, 2009